Pt. 63, Subpt. NNNNN, Table 1

- (1) A leak from equipment in HCl service subject to this subpart.
- (2) An exit from a control device used to comply with this subpart.
- (3) An HCl storage tank vent or HCl transfer operation vent subject to this subpart.
- (4) A HCl wastewater operation vent subject to this subpart.
- (5) A point of discharge from a relief valve.
- (6) A point of discharge from an analyzer.

HCl production facility is defined in $\S63.8985(a)(1)$.

HCl production unit means an absorber or other vessel in which a liquid HCl product is manufactured by absorbing gaseous HCl into either water or an aqueous HCl solution.

HCl storage tank means a tank or other vessel that is used to store liquid HCl product. Tanks or vessels permanently attached to motor vehicles (such as trucks, railcars, barges, or ships) are not HCl storage tanks.

HCl transfer operation means the loading, into a tank truck, railcar, ship, or barge, of liquid HCl from a transfer (or loading) rack (as defined in this section) for which the predominant use of a liquid HCl. The predominant use of a transfer (or loading) rack is the material that is loaded by the transfer (or loading) rack in the greatest amount.

HCl wastewater operation means an operation that handles and processes water containing HCl that is discarded from an HCl production facility.

Plant site means all contiguous or adjoining property that is under common control, including properties that are separated only by a road or other public right-of-way. Common control includes properties that are owned, leased, or operated by the same entity, parent entity, subsidiary, or any combination thereof.

Research and development facility means laboratory and pilot plant operations whose primary purpose is to conduct research and development into new processes and products, where the operations are under close supervision of technically trained personnel, and the operations are not engaged in the manufacture of products for commercial sale, except in a de minimis manner.

Responsible official means responsible official as defined in 40 CFR 70.2 of this chapter.

Transfer (or loading) rack means the collection of loading arms and loading hoses, at a single loading rack, that are used to fill tank trucks, railcars, ships, and/or barges. Transfer rack includes the associated pumps, meters, shutoff valves, relief valves, and other piping and valves.

Vapor balanced means connected to a piping system that is designed to collect vapors displaced from tank trucks, rail cars, ships, or barges during loading, and to route the collected vapors to the storage vessel from which the liquid being loaded originated, or to another storage vessel connected by a common header.

Vent means the point of discharge to the atmosphere or to a control device from either an HCl process vent, an HCl storage tank, or an HCl transfer operation.

Water scrubber control device means any add-on device that mixes an aqueous stream not containing a caustic substance with the exhaust gases from an HCl process vent, HCl storage tank, or HCl transfer operation to control emissions of HCl and/or Cl₂.

[68 FR 19090, Apr. 17, 2003, as amended at 71 FR 17746, Apr. 7, 2006]

Table 1 to Subpart NNNNN of Part 63—Emission Limits and Work Practice Standards

As stated in §63.9000(a), you must comply with the following emission limits and work practice standards for each emission stream that is part of an affected source.

For each . . .

You must meet the following emission limit and work practice standard

a. Reduce HCl emissions by 99 percent or greater or achieve an outlet concentration of 20 ppm by volume or less; and

Emission stream from an HCl process vent at an existing source.

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Pt. 63, Subpt. NNNNN, Table 3

For each	You must meet the following emission limit and work practice standard	
Emission stream from an HCl storge tank at an existing source. Emission stream from an HCl transfer operation at an existing source. Emission stream from leaking equipment in HCl service at existing and new sources.	 b. Reduce Cl₂ emissions by 99 percent or greater or achieve an outlet concentration of 100 ppm by volume or less. Reduce HCl emissions by 99 percent or greater or achieve an outlet concentration of 120 ppm by volume or less. Reduce HCl emissions by 99 percent or greater or achieve an outlet concentration of 120 ppm by volume or less. a. Prepare and operate at all times according to an equipment LDAR plan that describes in detail the measures that will be put in place to detect leaks and repair them in a timely fashion; and 	
	b. Submit the plan to the Administrator for comment only with your Notification of Compliance Status; and c. You may incorporate by reference in such plan existing manuals that describe the measures in place to control leaking equipment emissions required as part of other federally enforceable requirements, provided that all manuals that are incorporated by reference are submitted to the Administrator.	
5. Emission stream from an HCl process vent at a new source	Reduce HCl emissions by 99.4 percent or greater or achieve an outlet concentration of 12 ppm by volume or less; and Reduce Cl ₂ emissions by 99.8 percent or greater or achieve an outlet concentration of 20 ppm by volume or less.	
6. Emission stream from an HCl storage tank at a new source	Reduce HCl emissions by 99.9 percent or greater or achieve an outlet concentration of 12 ppm by volume or less.	
7. Emission stream from an HCI transfer operation at a new source.	Reduce HCI emissions by 99 percent or greater or achieve an outlet concentration of 120 ppm by volume or less.	

 $[68\;\mathrm{FR}\;19090,\,\mathrm{Apr.}\;17,\,2003,\,\mathrm{as}\;\mathrm{amended}\;\mathrm{at}\;71\;\mathrm{FR}\;17746,\,\mathrm{Apr.}\;7,\,2006]$

TABLE 2 TO SUBPART NNNNN OF PART 63—OPERATING LIMITS

As stated in $\S63.9000(b)$, you must comply with the following operating limits for each emission stream that is part of an affected source that is vented to a control device.

For each	You must	
Caustic scrubber or water scrubber/absorber	a. Maintain the daily average scrubber inlet liquid or recirculating liquid flow rate, as appropriate, above the operating limit; and b. Maintain the daily average scrubber effluent pH within the operating limits; or c. Instead of a. and b., maintain your operating parameter(s) within the operating limits established according to your monitoring plan established under § 63.8(f).	
Other type of control device to which HCl emissions are ducted.	Maintain your operating parameter(s) within the limits established during the performance test and according to your monitoring plan.	

Table 3 to Subpart NNNNN of Part 63—Performance Test Requirements for HCL Production Affected Sources

As stated in $\S63.9020$, you must comply with the following requirements for performance tests for HCl production for each affected source.

For each HCl process vent and each HCl storage tank and HCl transfer operation for which you are conducting a performance test, you must	Using	Additional Information
Select sampling port location(s) and the number of traverse points.	a. Method 1 or 1A in appendix A to 40 CFR part 60 of this chapter.	i. If complying with a percent reduction emission limitation, sampling sites must located at the inlet and outlet of the control device prior to any releases to the atmosphere (or, if a series of control devices are used, at the inlet of the first control device and at the outlet of the final control device prior to any releases to the atmosphere); or